

## List of Publications

### Books and Book Chapters

1. P.M.Sarro, Thermal Radiation Sensors, in 'Thermal Sensors', G.C.M.Meijer and A.W.van Herwaarden Ed., IOP Publishing Ltd. 1994, pp.152 - 161.
2. P.M. Sarro; M3: the third dimension of silicon, Advanced Micro & Nanosystems, Vol 1: Enabling Technologies for MEMS and Nanodevices, Baltes, Brand, Fedder, Hierold, Korvinck, Tabata Eds., WILEY-VCH, 2004, pp.1-19.(ISBN 3-527-30746-X)
3. P.M.Sarro, L.Wang and T.N.Nguyen, Through-chip connections, Chapter 11 in "3D Nanocomputer Architecture and Implementation", Ed. D Crawley; K Nikolic; M Forshaw, IOP publishing, September 2005, ISBN 0750310030, pp.247-265.
4. P.M.Sarro and P.J.French, Micromachining Technology: Bulk micromachining, Chpt.15 in 'MEMS, A practical guide to Design, Analysis and Applications', J.G.Korvinck and O.Paul Eds., William Andrew Publishing, USA, 2006, ISBN 0-8155-1497-2.
5. P.M.Sarro, A.Irace and P.J.French, Micromachining Technologies for Sensor Applications, Chapter 8 in "Introduction to Optoelectronic Sensors", G.C.Righini, A.Tajani, A.Cutolo Eds., World Scientific, 2009, ISBN 978-981-283-412-6.

### Journal papers

1. R.R.Arya, P.M.Sarro, J.J.Loferski, Efficient Cadmium Sulfide on Silicon Solar Cells, Appl.Phys.Lett., 41 (1982) 355-357.
2. JJ Loferski, C Case, M Kwietniak, PM Sarro, L Castaner, R Beaulieu, Comparison of properties of thin films of CuInSe<sub>2</sub> and its alloys produced by evaporation, RF-sputtering and chemical spray pyrolysis, Applications of surface science, 1985, vol. 22, 645-655
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10. P.M.Sarro, H.Yashiro, A.W.van Herwaarden, S.Middelhoek, An Integrated Thermal Infrared Sensing Array, Sensors and Actuators, 14 (1988) 191-201.
11. A.W.vanHerwaarden, P.M.Sarro, Integrated Thermal Vacuum Sensor with Extended Range, Vacuum, 38 (1988) 449-453.
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